What is claimed is:

1. A wafer chuck comprising:

a. a chuck body having:

i. a wafer holding face for holding a wafer;

ii. a cavity structurally separated and below said wafer holding face;

iii. at least three pin channels extending between said holding face and said cavity substantially perpendicular to said holding face;

b. at least three pinlifters correspondingly shaped to and slide ably embedded in said pin channels, each of said pinlifters having a bottom face and a top face;

c. a pinlifter assembly embedded in said cavity, said pinlifter assembly having:

i. a wedge guide providing an angled movement path that is in an wedge angle with respect to said wafer holding face;

ii. a pin actuator correspondingly shaped to said wedge guide and slide ably guided by said wedge guide such that said pin actuator is moved along said movement path as a result of an imposed driving force;

iii. a driving means for said imposing of said driving force onto said pin actuator;

wherein said bottom faces are in contact with a pin contact face of said pin actuator such that said pinlifters are simultaneously moved along said pin channels and said top faces are moved between a bottom position below said holding face and a top position above said holding face while said pin actuator is moved along said movement path.

2. The wafer chuck of claim 1, wherein said guides are provided by guide structures attached inside said cavity to said chuck body.

3. The wafer chuck of claim 1, wherein said guides are integral part of a shape of said cavity.

4. The wafer chuck of claim 1, wherein said pin contact face is substantially parallel to said holding face.

5. The wafer chuck of claim 1, wherein said pin contact face is angled with respect to said holding face and said wedge angle is substantially zero.

6. The wafer chuck of claim 1, wherein said guides are linear such that said movement path is linear.

7. The wafer chuck of claim 1, wherein said guides are circular and rotationally symmetric arranged such that said movement path is a rotation.

8. The wafer chuck of claim 7, wherein said guides are arranged such that a rotation axis of said movement path substantially coincides with a center axis of said wafer chuck.

9. The wafer chuck of claim 1 further comprising a vacuum connect having a vacuum channel for connecting a vacuum across said cavity to a vacuum groove recessed from said wafer holding face.

10. The wafer chuck of claim 2, wherein said pin actuator has a cutout such that said pin actuator may be moved between two end positions without interfering with said vacuum connect.

11. The wafer chuck of claim 1, wherein said driving means include a motored rotating crank and a connecting rod transmitting a rotating motion of said motored rotating crank onto said pin actuator.

12. The wafer chuck of claim 4, wherein said driving crank is motored by a stepper motor.

13. The wafer chuck of claim 6, wherein said stepper motor has a rotation axis that is substantially perpendicular to said wafer holding face.

14. The wafer chuck of claim 1, wherein said cavity is substantially sealed and communicating a vacuum substantially unimpeded between a vacuum channel and a vacuum connect, said vacuum channel connecting said cavity with a vacuum groove recessed from said wafer holding face, said vacuum connect extending from a bottom face of said wafer chuck.

15. The wafer chuck of claim 1 being part of a rotary stage.

16. The wafer chuck of claim 15, wherein said cavity is at least partially provided by said rotary stage.

17. The wafer chuck of claim 1 being part of a single axis linear stage.

18. The wafer chuck of claim 17, wherein said cavity is at least partially provided by said single axis linear stage.

19. The wafer chuck of claim 1 being part of a dual axis linear stage.

20. The wafer chuck of claim 19, wherein said cavity is at least partially provided by said dual axis linear stage.

21. The wafer chuck of claim 1 being part of a wafer testing device.